



Subst. Form PTO-1449 APPLICANT'S(S') INFORMATION DISCLOSURE STATEMENT	Atty. Docket No.: D/A0597 XER 2 0368	Serial No.: 09/725,836
	Applicant(s): Decai Sun, et al.	
	Filing Date: November 29, 2000	Group: 2831

U.S. PATENT DOCUMENTS

Initial*	Document No.	Date	Name	Class	Subcl.	Filing Date
AA	6,243,194 B1	05JE2001	Brazas, Jr. et al.			
AB	6,456,420 B1	24SE2002	Goodwin-Johansson			
AC	6,299,462 B1	09OC2001	Biegelsen			
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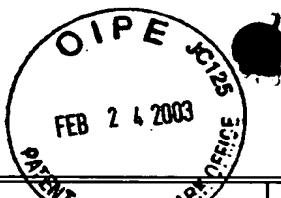
	Document No.	Date	Country	Class	Subcl.	Translation?
AL	WO 94/03786	17FE1994	PCT			English
AM	EP 0 502 222 A1	09SE1992	EPC			English
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AR	European Search Report; Application No. 01127498.2-1524; 09 April 2002; Examiner Michel, A.	
AS	MOTAMEDI, M. Edward; <i>Development of Micro-Electro-Mechanical Optical Scanner</i> ; Society of Photo Optical Instrumentation Engineers, 36(5) pp. 1346-1353 (May 1997);	
AT	European Search Report; Application No. 01127729.0-2217; 09 April 2002; Examiner Michel, A.	

 Examiner: *Jinhee Lee* Date Considered: *3/14/03*

* EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if in conformance and not considered. Include copy of this form with next communication to applicant.



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BQ	WIBBELER et al.; <i>Parasitic Charging of Dielectric Surfaces in Capacitive Micro-Electro-Mechanical Systems (MEMS)</i> ; <i>Sensors and Actuators A</i> , 71 (1998) 74-80.	
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BS	SYMS, Richard R. A.; <i>Refractive Collimating Microlens Arrays by Surface Tension Self-Assembly</i> ; <i>IEEE Photonics Technology Letters</i> , Vol. 12, No. 11, November 2000, pp. 1507-1509.	

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